ABSTRACT

SELF ALIGNING WAFER CHUCK DESIGN FOR WAFER PROCESSING TOOLS

A wafer chuck for positioning and releasably holding a wafer includes a support platform having an upper surface means for positioning and supporting thereon the wafer; wafer banking pins affixed to the support platform used for positioning the wafer, a lift device acting on the wafer when it rests on the support platform to move the wafer relative to the support platform in a biased direction away from the support platform and wafer banking pins, the lift device having a plurality of wafer lifting fingers that cooperatively extend in a biased and substantially vertical direction are disposed in a pattern to be supportive of the wafer, each of the wafer lifting fingers having an end portion movable, relative to the support platform, between a first position at which it is retracted from the upper surface of the support platform and a second position at which it protrudes from the upper surface of the support platform so as to engage the wafer to lift it relative to the support platform.

(FIGURE 1 IS SUGGESTED FOR PUBLICATION)

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